

High functionality of an optical fiber stylus for micro metrology

Hiroshi Murakami¹, Akio Katsuki², Takao Sajima², Kosuke Uchiyama¹, Takahiko Yamamoto³, Ryosuke Nagata³ and Kunitaka Fujiyoshi⁴

¹*The University of Kitakyushu, Japan*

²*Kyushu University, Japan*

³*Inatsuki Science Co., Ltd., Japan*

⁴*Fukuoka Industrial Technology Center, Japan*

Abstract

We aim to develop a highly accurate measurement system with a low measurement force using a micro optical fiber probe. In this research, we conducted performance test of water repellent and antistatic coating on a stylus tip to prevent adhesion to the measured surface by surface forces, in addition to durability tests. As a result, when a stylus tip with a water repellent coating was used, the separation distance from the target surface was shorter by approximately 78% compared with the uncoated tip. Also, when a stylus tip with an antistatic coating was used, the adsorption and separation distances were reduced by 84% and 77% compared with the uncoated tip.

1 Introduction

Recent years have witnessed an increased demand for a method for precise measurement of the microstructures of mechanical microparts, microelectromechanical systems, micromolds, optical devices, microholes, *etc.* Therefore, we aim to develop a highly accurate measurement system with low measurement forces by using a micro optical fiber probe. In this research, we conducted performance test of water repellent and antistatic coating on a stylus tip to prevent adhesion to the measured surface by surface forces, in addition to durability tests.

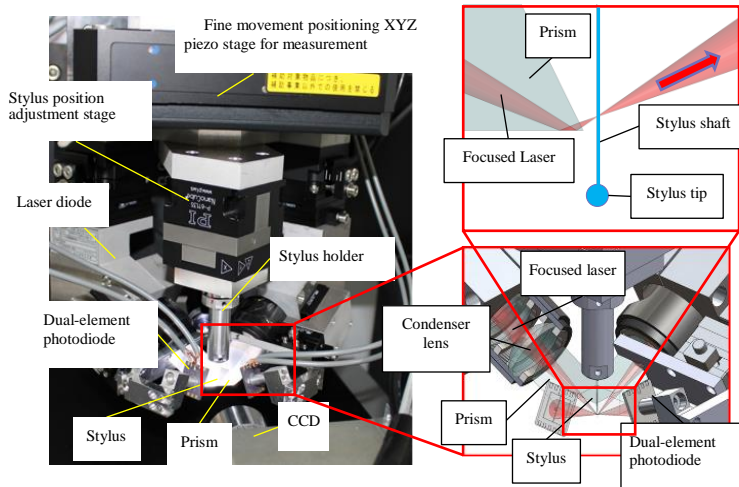


Figure 1: Overview of the measurement system

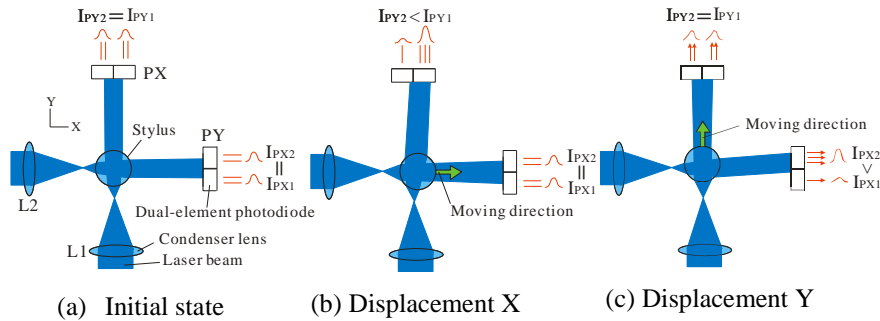


Figure 2: Measurement principle

2 Principles of measurement

Figure 1 shows an image of the measurement system and a schematic of the laser-irradiated portion of the stylus. Figure 2 shows a cross-sectional view of Fig. 1 in the XY plane as well as the measurement principle of the optical fiber probe. A focused laser light is irradiated in the XY direction toward the shaft of the stylus. The diameter of the stylus is reduced by acid etching and the tip of it is irradiated with a CO₂ laser to generate a stylus tip [1]. The laser transmitted through the stylus shaft is received by two pairs of dual-element photodiodes installed on opposite sides with the stylus in between. Before the stylus tip comes into contact with the measured surface, the light intensities measured using each element of the dual-element photodiode are equal, as shown in Fig. 2 (a). When the stylus tip contacts the measured surface in the X direction, the stylus shaft is displaced, and the light intensities of each element of the dual-element photodiode becomes unequal, as shown in Fig. 2 (b). When the stylus shaft is displaced in the +X direction, the angle of refraction of the laser beam passing through the stylus shaft in the Y direction changes because of a shift in the irradiated section of the stylus shaft.

tip between the tip and the hole sidewall (Through-Silicon Via, TSV) on the silicon wafer was performed. In the approach, a tip was brought into contact with the side wall of the TSV hole. Furthermore, a force was applied to stylus shaft until it was deflected by 5 μm . Thereafter, pseudo-contact was reproduced by oscillating the tip in the vertical direction of the hole at an amplitude of 10 μm and a vibration frequency of 4 Hz. The contact counts were 10 000, 100 000 and 300 000 times. As a result, there is no change in separation distance even when the stylus comes into contact 300 000 times.

3.2 Antistatic coating

Au coating is formed on the surface of a stylus tip to remove the static electricity. The film thickness of au coating is 3 nm. A peeling test for a charged surface (-2 kV) and a stylus tip was performed as shown in Fig. 6. When the stylus approaches the charged surface, the stylus tip is adsorbed to the surface by static electricity. The distance between the stylus tip and the measured surface is defined as D_a as shown in Fig. 6. When the system detects the overtravel signal, the stylus tip is displaced in backward direction. As a result, the stylus tip can be separated from the measured surface when the displacement D_s of the stylus tip exceeds a certain value. The results are shown in Fig. 7. It is confirmed that the adsorption and separation distances were reduced by 84% and 77%, and the antistatic coating is effective at reducing the electrostatic force. The effect of liquid bridging force remains in the results of the adsorption and separation distances with coating. Figure 8 shows the schematic diagram of the stylus coated with a double layer of the antistatic and water repellent coating. Thus, we plan to apply the coating to the stylus in two layers in order to be able to eliminate both effects in the future. Also, we plan to conduct an abrasion resistance test of the antistatic coating in the future.

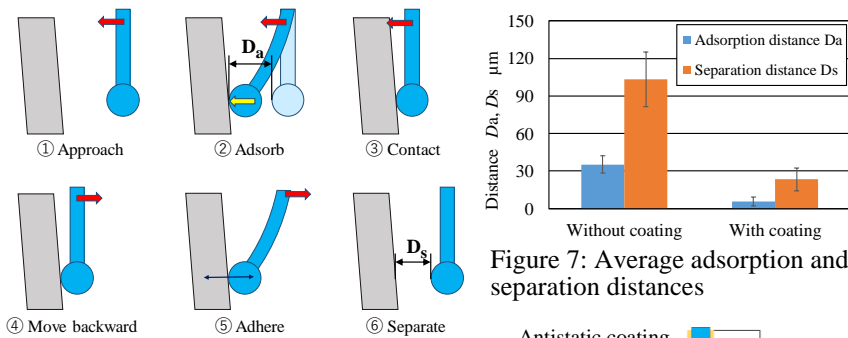


Figure 6: Experimental apparatus for measurement of electrostatic forces

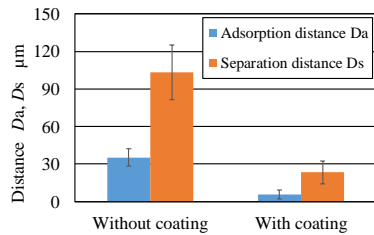


Figure 7: Average adsorption and separation distances

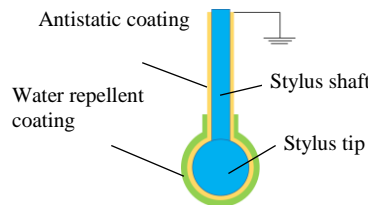


Figure 8: Schematic diagram of antistatic and water repellent coating

4 Conclusion

When a stylus tip with a water repellent coating was used, the separation distance from the target surface was shorter by approximately 78% compared with the uncoated tip. Also, when a stylus tip with an antistatic coating was used, the adsorption and separation distance were reduced by 84% and 77% compared with the uncoated tip. In the future, we plan to investigate the sphericity of the stylus tip fabricated by the CO₂ laser and the influences of coating on the sphericity of the stylus.

Acknowledgments

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